

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Priority Group Art Unit ..... 2825  
Priority Examiner ..... G. Lee  
Attorney's Docket No. ..... MI22-1421  
Title: Methods of Forming Silicon Dioxide Layers, and Methods of Forming  
Trench Isolation Regions

To: Mail Stop Patent Application  
Commissioner for Patents  
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PRELIMINARY AMENDMENT

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